

## AMENDMENTS TO THE SPECIFICATION

Paragraph beginning of line 22 of page 19 is amended as follows:

The susceptor system including vacuum pumping mechanism shown in Figure 2A disposed within a processing chamber **133** comprises the susceptor **135** which includes the susceptor shaft **137** and a substrate support plate **20**, a motor **14**, a shaft vacuum connector housing **16** and a controller **170**. The support plate **20** includes a top plate **40**, a base plate ~~[[20]]~~ **42** and braised region **44** therebetween; the top and base portions may also be joined by welding or other equivalent techniques. The support plate **20** may contain heating element(s) **24** disposed between the top plate **40** and the base plate ~~[[20]]~~ **42**.